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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : YEH
Application No. : 10/601,701
Filed : June 24, 2003
Title : METHOD FOR FABRICATION OF POLYCRYSTALLINE
SILICON THIN FILM TRANSISTORS
Group Art Unit : 2812
Examiner : S. Isaac
Docket No. : 3230-56

MAIL STOP AMENDMENT

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL COVER SHEET

Sir:

Transmitted herewith for filing are the following:

1. AMENDMENT - in response to Office Action of February 10, 2006.

The Commissioner is hereby authorized to charge any fees which may be required for the filing of this document to Deposit Account No. 501874.

Respectfully submitted,

Date: March 31, 2006

By:

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Reg. No. 26,592

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Application No. 10/601,701

Attorney Docket: 3230-56

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : YEH
Application No. : 10/601,701
Filed : June 24, 2003
Title : Method for Fabrication of Polycrystalline Silicon Thin
Film Transistors (As Amended)
Group Art Unit : 2812
Examiner : S. Isaac
Docket No. : 3230-56

MAIL STOP AMENDMENT

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action of February 10, 2006, the period for response to which is set to expire on **April 10, 2006**, please amend the above-identified application as follows: